

Amendments to the Claims

Claim 1 (currently amended): A device for mounting a substrate to be coated in a ~~hydrogen-containing~~ gaseous atmosphere, comprising:

a susceptor for supporting a substrate to be coated in the ~~hydrogen-containing~~ gaseous atmosphere;

said susceptor including an insert having a surface and including a graphite core; and

a metal carbide layer of a given thickness covering said graphite core, said metal carbide layer including one carbide selected from the group consisting of tantalum carbide, niobium carbide, tungsten carbide, molybdenum carbide, chromium carbide, vanadium carbide and hafnium carbide and forming at least a portion of said surface, said portion supporting the substrate, ~~said metal carbon layer being inert with respect to the hydrogen of the gaseous atmosphere.~~

Claim 2 (original): The device according to claim 1, wherein said insert includes a plurality of tiles, each of said tiles being provided for a respective substrate.

Claim 3 (original): The device according to claim 2, wherein each of said tiles is formed with a depression for the respective substrate.

Claims 4-10 (cancelled).

Claim 11 (withdrawn): A method for producing an insert for a susceptor, the method which comprises:

producing a metallic preform;

embedding the metallic preform in a carbon-containing powder;

heating the metallic preform and the carbon-containing powder to an elevated temperature for providing a heat-treated preform;

hard processing the heat-treated preform for providing a hard-processed preform having a surface layer made of a metal carbide; and

disposing the hard-processed preform as an insert on a susceptor.

Claim 12 (withdrawn): The method according to claim 11, which comprises performing the heating step under an elevated pressure.

Claim 13 (withdrawn): The method according to claim 11, which comprises heating the metallic preform and the carbon-containing powder to the elevated temperature of between 1500°C and 2000°C.

Claim 14 (withdrawn): The method according to claim 11, which comprises using a silicon carbide powder as the carbon-containing powder.

Claim 15 (original): The device according to claim 1, wherein said portion of said surface of said metal carbide layer is in direct proximity to the substrate, when the substrate is mounted thereon, for preventing contaminating material from diffusing into the substrate through said portion of said surface.

Claim 16 (new): The device according to claim 1, wherein said substrate is to be silicon carbide coated.

Claim 17 (new): The device according to claim 1, wherein said substrate includes silicon carbide.

Claim 18 (new): The device according to claim 1, wherein said gaseous atmosphere contains hydrogen.

Claim 19 (new): A device for mounting a substrate including silicon carbide and to be silicon carbide coated in a hydrogen containing gaseous atmosphere, comprising:

a susceptor for supporting a substrate to be coated in the hydrogen containing gaseous atmosphere;

said susceptor including an insert having a surface; and

a metal carbide layer of a given thickness forming at least a portion of said surface, said portion supporting the substrate, said metal carbon layer being inert with respect to the hydrogen of the gaseous atmosphere.

Claim 20 (new): The device according to claim 19, wherein said insert includes a plurality of tiles, each of said tiles being provided for a respective substrate.

Claim 21 (new): The device according to claim 20, wherein each of said tiles is formed with a depression for the respective substrate.

Claim 22 (new): The device according to claim 19, wherein said insert includes a graphite core, said metal carbide layer covers said graphite core.

Claim 23 (new): The device according to claim 19, wherein said insert includes a metal core, said metal carbide layer covers said metal core.

Claim 24 (new): The device according to claim 19, wherein said metal carbide layer includes one carbide selected from the group consisting of tantalum carbide, niobium carbide, tungsten carbide, molybdenum carbide, chromium carbide, vanadium carbide and hafnium carbide.

Claim 25 (new): The device according to claim 19, wherein said portion of said surface of said metal carbide layer is in direct proximity to the substrate, when the substrate is mounted thereon, for preventing contaminating material from diffusing into the substrate through said portion of said surface.